



Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 3

Complete If Known

| | |
|------------------------|--------------------|
| Application Number | 10/791,633 |
| Filing Date | 03/01/2004 |
| First Named Inventor | Maalouf, Khalil J. |
| Art Unit | Not yet known |
| Examiner Name | Not yet known |
| Attorney Docket Number | 019930-002510US |

U.S. PATENT DOCUMENTS+

| Examiner Initials* | Cite No. ¹ | Document Number | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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|--------------------|-----------------------|---------------------------|---------------------|-----------------------------------|--------------------------------|--|--|--------------------------|
| | | Country Code ³ | Number ⁴ | Kind Code ⁵ (if known) | | | | |
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| B2 | | | | | | | | <input type="checkbox"/> |
| B3 | | | | | | | | <input type="checkbox"/> |

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|--------------------|----------------------------|-----------------|----------------|
| Examiner Signature | <i>John T. [Signature]</i> | Date Considered | <i>4/17/05</i> |
|--------------------|----------------------------|-----------------|----------------|

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| | | | | <i>First Named Inventor</i> | Maalouf, Khalil J. |
| | | | | <i>Art Unit</i> | Not yet known |
| | | | | <i>Examiner Name</i> | Not yet known |
| Sheet | 2 | of | 3 | <i>Attorney Docket Number</i> | 019930-002510US |

| NON PATENT LITERATURE DOCUMENTS | | | | | |
|--|-----------------------|---|--|--|----------------|
| Examiner Initials * | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | | | |
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|--------------------|------------------|-----------------|--------|
| Examiner Signature | <i>Anil Jain</i> | Date Considered | 4/7/05 |
|--------------------|------------------|-----------------|--------|

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¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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